

Day : Friday  
Date: 12/19/2003

Time: 12:00:57

# PALM INTRANET

## Inventor Name Search Result

Your Search was:

Last Name = SAKAMA

First Name = MITSUNORI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10367819 20030151119	Not Issued 0826	092 257/639	02/19/2003	SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME	SAKAMA, MITSUNORI
10337724	Not Issued	020	01/08/2003	SEMICONDUCTOR DEVICE, AND METHOD OF FABRICATING THE SAME	SAKAMA, MITSUNORI
10302500 20030060485	Not Issued	041 118/723 E	11/25/2002	PLASMA CVD APPARATUS	SAKAMA, MITSUNORI
10164019	Not Issued	030 New	06/07/2002	SUBSTRATE PROCESSING APPARATUS AND METHOD AND A MANUFACTURING METHOD OF A THIN FILM SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI JFW
10125954	6593235	150	04/18/2002	A PROCESS FOR PRODUCING A SEMICONDUCTOR DEVICE WITH A TAPERED HOLE FORMED USING MULTIPLE LAYERS WITH DIFFERENT ETCHING RATES	SAKAMA, MITSUNORI
10084935 20020153065	Not Issued	061	03/01/2002	INSULATING FILM AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
10037865 20020117090 438/790	Not Issued 0813	094 at pub.	10/24/2001	AN APCVD METHOD OF FORMING SILICON OXIDE USING AN ORGANIC SILANE, OXIDIZING AGENT, AND CATALYST-FORMED HYDROGEN RADICAL	SAKAMA, MITSUNORI all method c but differ plasma process relat concerns
09935660 176211	6499427	150	08/24/2001	PLASMA CVD APPARATUS - JFW only shows PACR screen	SAKAMA, MITSUNORI
09917095 2002006711	Not Issued	092	07/26/2001	PLASMA CVD METHOD Term. de. l. 6, 281, 147	SAKAMA, MITSUNORI
09852063	Not Issued	093 New 0813	05/08/2001	METHOD OF MANUFACTURING	SAKAMA, JFW

	Issued			A SEMICONDUCTOR DEVICE	mitsunori
09771625	6673659 2811 438/149	150	01/30/2001	SEMICONDUCTOR DEVICE AND METHOD OF PRODUCING THE SAME	SAKAMA, MITSUNORI
09739269	6632708 2811 438/158	150	12/19/2000	SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME	SAKAMA, MITSUNORI
09703593	6521912 2823 257/57	150	11/02/2000	SEMICONDUCTOR DEVICE, AND METHOD OF FABRICATING THE SAME	SAKAMA, MITSUNORI
09609357	6634562	150	07/05/2000	RECORDING AND REPRODUCING APPARATUS, RECORDING MEDIUM ADAPTER APPARATUS, AND RECORDING AND REPRODUCING METHOD	SAKAMA, MITSUNORI
09584617	Not Issued 2813 438/164	061	05/31/2000	SEMICONDUCTOR DEVICE AND A METHOD OF MANUFACTURING THE SAME	SAKAMA, MITSUNORI NOT NO IFW pre-pub
09554803	Not Issued	095	07/27/2000	RECORDING MEDIUM DEVICE CONTAINING RECORDING MEDIUM AND RECORDING/REPRODUCING DEVICE	SAKAMA, MITSUNORI
09532915	Not Issued 2822 257/347	041	03/22/2000	SEMICONDUCTOR DEVICE AND METHOD FOR MANUFACTURING THE SAME	SAKAMA, MITSUNORI NOT NO IFW pre-pub
09190828	6025630	150	11/12/1998	INSULATING FILM FORMED USING AN ORGANIC SILANE AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08734127	5866932 2815 257/347	150	10/21/1996	INSULATING FILM FORMED USING AN ORGANIC SILANE AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08685788	6482752 2813 438/158	150	07/24/1996	SUBSTRATE PROCESSING APPARATUS AND METHOD AND A MANUFACTURING METHOD OF A THIN FILM SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08666104	6396078	150	06/19/1996	A SEMICONDUCTOR DEVICE WITH A TAPERED HOLE FORMED USING MULTIPLE LAYERS WITH DIFFERENT ETCHING RATES	SAKAMA, MITSUNORI
08396583	Not	071	03/01/1995	LIQUID CRYSTAL DEVICE	SAKAMA,

	Issued			WITH A FERROELECTRIC THIN FILM	mitsunori
<del>08396582</del>	Not Issued	161	03/01/1995	LIQUID CRYSTAL DEVICE WITH AN APPARENT HYSTERESIS	SAKAMA , MITSUNORI
<del>08388684</del>	Not Issued	161	02/15/1995	METHOD FOR MAKING A HIGH CONTRAST LIQUID CRYSTAL DISPLAY INCLUDING LASER SCRIBING OPAQUE AND TRANSPARENT CONDUCTIVE STRIPS SIMULTANEOUSLY	SAKAMA , MITSUNORI
08372900	Not Issued	161	01/17/1995	ETCHING APPARATUS	SAKAMA , MITSUNORI
07859168	Not Issued	166	03/27/1992	LIQUID CRYSTAL DEVICE WITH A FERROELECTRIC THIN FILM	SAKAMA , MITSUNORI
07858602	Not Issued	166	03/27/1992	LIQUID CRYSTAL DEVICE WITH AN APPARENT HYSTERESIS	SAKAMA , MITSUNORI
07849738	5330578 11/10/93	150 11/8/93	03/11/1992	PLASMA TREATMENT APPARATUS	SAKAMA , MITSUNORI
07807748	5187601	150	12/17/1991	METHOD FOR MAKING A HIGH CONTRAST LIQUID CRYSTAL DISPLAY INCLUDING LASER SCRIBING OPRQUE AND TRANSPARENT CONDUCTIVE STRIPS SIMULTANEOUSLY	SAKAMA , MITSUNORI
07554342	5091638	150	07/19/1990	CONTACT IMAGE SENSOR HAVING LIGHT-RECEIVING WINDOWS	SAKAMA , MITSUNORI
07525734	5043567	150	05/21/1990	IMAGE SENSOR AND MANUFACTURING METHOD FOR THE SAME	SAKAMA , MITSUNORI
07498474	5036794	250	03/23/1990	CVD APPARATUS	SAKAMA , MITSUNORI
07394265	4995706	150	08/14/1989	LIQUID CRYSTAL DEVICE WITH A FERROELECTRIC THIN FILM	SAKAMA , MITSUNORI
07385927	5069531	150	07/27/1989	LIQUID CRYSTAL DEVICE HAVING ASYMMETRICAL OPPOSED CONTIGUOUS SURFACES BEING DRIVEN BY A UNIPOLAR DRIVING SOURCE	SAKAMA , MITSUNORI
07324669	5079031 477/138	150	03/17/1989	APPARATUS AND METHOD FOR FORMING THIN FILMS	SAKAMA , MITSUNORI

1309

Day : Friday  
Date: 12/19/2003

## PALM INTRANET

Time: 12:16:09

## Inventor Name Search Result

Your Search was:

Last Name = SAKAMA

First Name = MITSUNORI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
09466828	Not Issued 438	093 784	12/20/1999 Au 2818	INSULATING FILM AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI IFW
09457128	(6281147) 1382	150 1245	12/07/1999	PLASMA CVD METHOD	SAKAMA, MITSUNORI
09294338	6268631	150	04/20/1999	GLASS-SUBSTRATE ASSEMBLY, SEMICONDUCTOR DEVICE AND METHOD OF HEAT-TREATING GLASS SUBSTRATE	SAKAMA, MITSUNORI
09286999	6635589	150	04/07/1999	METHODS OF HEAT TREATMENT AND HEAT TREATMENT APPARATUS FOR SILICON OXIDE FILMS	SAKAMA, MITSUNORI
09070908	Not Issued	121	05/04/1998	FILM FORMING METHOD AND FILM FORMING APPARATUS	SAKAMA, MITSUNORI
09069942	(6283060) 1403	150 1181	04/30/1998 715	PLASMA CVD APPARATUS	SAKAMA, MITSUNORI
08973760	6160679	150	04/13/1998	RECORDING MEDIUM DEVICE FOR USE WITH A TAPE CARTRIDGE HAVING AN AUXILIARY MEMORY VIEWABLE THROUGH A CARTRIDGE DISCRIMINATION OPENING	SAKAMA, MITSUNORI
08791474	Not Issued	(161)	01/27/1997	PLASMA PROCESSING METHOD	SAKAMA, MITSUNORI
08781930	(5837614) 2813 438/789	150	01/07/1997	INSULATING FILM AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08748233	6015762	150	11/12/1996	PLASMA CVD METHOD	SAKAMA,

<del>07295009</del>	Not Issued	160	01/09/1989	LIQUID CRYSTAL DEVICE WITH A FERROELECTRIC THIN FILM	SAKAMA , MITSUNORI
07295008	4978203	150	01/09/1989	LIQUID CRYSTAL DEVICE WITH AN APPARENT HYSTERESIS	SAKAMA , MITSUNORI
07285419	5014100	250	12/16/1988	IMAGE SENSOR FREE FROM UNDESIRABLE INCIDENT LIGHT RAYS WHICH HAVE NOT BEEN REFLECTED IN THE SURFACE BEARING THE IMAGE TO BE SENSED	SAKAMA , MITSUNORI
<del>07282850</del>	Not Issued	166	12/09/1988	LIQUID CRYSTAL DEVICE WITH A FERROELECTRIC THIN FILM	SAKAMA , MITSUNORI
07263367	4945226	150	10/27/1988	SEMICONDUCTOR PHOTOSENSOR AND DRIVING METHOD THEREFOR	SAKAMA , MITSUNORI
07259522	4959533	150	10/18/1988	PHOTOSENSITIVE SEMICONDUCTOR CONTACT IMAGE SENSOR	SAKAMA , MITSUNORI
07243218	5196954	150	09/12/1988	LIQUID CRYSTAL DISPLAY	SAKAMA , MITSUNORI
07211225	4943710 An 2503 250/208.1	250	06/22/1988	IMAGE SENSOR AND MANUFACTURING METHOD FOR THE SAME	SAKAMA , MITSUNORI
07135463	Not Issued	166	12/21/1987	CVD APPARATUS	SAKAMA , MITSUNORI
06934911	Not Issued	166	11/25/1986	LIQUID CRYSTAL DEVICE WITH A FERROELECTRIC THIN FILM	SAKAMA , MITSUNORI
06928489	Not Issued	166	11/10/1986	LIQUID CRYSTAL DEVICE AND MANUFACTURING METHOD FOR SAME	SAKAMA , MITSUNORI
06895029	Not Issued	166	08/08/1986	LIQUID CRYSTAL DISPLAY	SAKAMA , MITSUNORI
06885662	4691995	150	07/15/1986	LIQUID CRYSTAL FILLING DEVICE	SAKAMA , MITSUNORI
06875211	4828967	150	06/17/1986	ELECTRONIC DEVICE AND ITS MANUFACTURING METHOD	SAKAMA , MITSUNORI
06849293	4723508 118/223	150 1508	04/08/1986	PLASMA CVD APPARATUS	SAKAMA , MITSUNORI
<del>06849292</del>	Not Issued	166	04/08/1986	CVD APPARATUS	SAKAMA , MITSUNORI

[Search and Display More Records.](#)

					SAKAMA, MITSUNORI
08728161	5712744	150	10/09/1996	MAGNETIC TAPE LOADING DEVICE	SAKAMA, MITSUNORI
08706667	6228751 <i>80-2813 438/585</i>	150	09/06/1996	METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08706666	6323142 <i>2813 (438/790)</i>	150	09/06/1996	AN APCVD METHOD OF FORMING SILICON OXIDE USING AN ORGANIC SILANE, OXIDIZING AGENT, AND CATALYST-FORMED HYDROGEN RADICAL	SAKAMA, MITSUNORI <i>atmospheric Press 910-71</i>
08635951	5791578	150	07/01/1996	RECORDING MEDIUM DEVICE WITH MEMORY TERMINALS AND SHUTTER SIZED AND SHAPED IN RELATION THERETO	SAKAMA, MITSUNORI
08626579	Not Issued	161	04/02/1996	PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	SAKAMA, MITSUNORI
08572008	6337229 <i>80-2813 438/149</i>	150	12/14/1995	METHOD OF MAKING CRYSTAL SILICON SEMICONDUCTOR AND THIN FILM TRANSISTOR	SAKAMA, MITSUNORI
08521534	5840600 <i>80-1623 438/151</i>	150	08/30/1995	METHOD FOR PRODUCING SEMICONDUCTOR DEVICE AND APPARATUS FOR TREATING SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08510288	5970384	150	08/02/1995	METHODS OF HEAT TREATING SILICON OXIDE FILMS BY IRRADIATING ULTRA-VIOLET LIGHT	SAKAMA, MITSUNORI <i>cl.</i>
08498513	Not Issued	166	07/05/1995	PLASMA PROCESSING METHOD	SAKAMA, MITSUNORI
08498440	Not Issued	161	07/05/1995	METHOD OF DRY ETCHING	SAKAMA, MITSUNORI
08464125	Not Issued	161	06/05/1995	SUBSTRATE PROCESSING APPARATUS AND METHOD AND A MANUFACTURING METHOD OF A THIN FILM SEMICONDUCTOR DEVICE	SAKAMA, MITSUNORI
08462773	5929487	150	06/05/1995	GLASS SUBSTRATE ASSEMBLY, SEMICONDUCTOR DEVICE AND METHOD OF HEAT-	SAKAMA, MITSUNORI

				TREATING GLASS SUBSTRATE	
<u>08455574</u>	Not Issued	166	05/31/1995	INSULATING FILM FORMED USING AN ORGANIC SILANE AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA , MITSUNORI
<u>08321321</u>	Not Issued	166	10/11/1994	SUBSTRATE PROCESSING APPARATUS AND METHOD AND A MANUFACTURING METHOD OF A THIN FILM SEMICONDUCTOR DEVICE	SAKAMA , MITSUNORI
<u>08311275</u>	5674304 1303	150 05/32	09/23/1994	METHOD OF HEAT- TREATING A GLASS SUBSTRATE	SAKAMA , MITSUNORI
<u>08297119</u>	Not Issued	166	08/26/1994	PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	SAKAMA , MITSUNORI
<u>08198054</u>	Not Issued	166	02/18/1994	INSULATING FILM AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE	SAKAMA , MITSUNORI
<u>07982980</u>	5353140	150	11/30/1992	LIQUID CRYSTAL DISPLAY	SAKAMA , MITSUNORI
<u>07679135</u>	5109292	150	03/28/1991	LIQUID CRYSTAL DEVICE HAVING RESIN LAYER FORMED BETWEEN ADJACENT ACTIVE ELEMENTS	SAKAMA , MITSUNORI
<u>07572331</u>	5096851	150	08/24/1990	A METHOD OF PACKAGING AN ELECTRONIC DEVICE USING A COMMON HOLDER TO CARRY THE DEVICE IN BOTH A CVD AND MOLDING STEP	SAKAMA , MITSUNORI
<u>07468069</u>	5017502	250	01/22/1990	IMAGE SENSOR AND MANUFACTURING METHOD FOR THE SAME	SAKAMA , MITSUNORI
<u>07355339</u>	Not Issued	166	05/23/1989	LIQUID CRYSTAL DEVICE AND MANUFACTURING METHOD FOR SAME	SAKAMA , MITSUNORI
<u>07353751</u>	Not Issued	166	05/18/1989	ELECTRIC DEVICE AND MANUFACTURING METHOD OF THE SAME	SAKAMA , MITSUNORI
<u>07342857</u>	5017828	150	04/25/1989	IMAGE SENSOR	SAKAMA , MITSUNORI
<u>07318540</u>	Not	166	03/03/1989	LIQUID CRYSTAL DISPLAY	SAKAMA ,

	Issued			CAPABLE OF PRODUCING HIGH CONTRAST IMAGES	mitsunori
X 07295008	4978203	150	01/09/1989	LIQUID CRYSTAL DEVICE WITH AN APPARENT HYSTERESIS	SAKAMA, mitsunori
X 07148097	4844588	150 2507 999/4999	01/25/1988	LIQUID CRYSTAL DISPLAY PANEL AND MANUFACTURING METHOD THEREOF	SAKAMA, mitsunori
X 07127433	4861143	150	12/02/1987	LIQUID CRYSTAL DISPLAY CAPABLE OF DISPLAYING GRAY TONE	SAKAMA, mitsunori
X 07124566	5039620	150 1184 999/3.0	11/24/1987	METHOD OF MAKING A PHOTOELECTRIC CONVERSION DEVICE WITH A HIGH RESPONSE SPEED	SAKAMA, mitsunori
X 07086646	4820612	150 Au 1508 430/315	08/18/1987	ELECTRONIC DEVICE AND ITS MANUFACTURING METHOD	SAKAMA, mitsunori
X 07082908	4780794 2105	150 361/401	08/10/1987	ELECTRONIC DEVICE	SAKAMA, mitsunori
X 07034165	4799776	150	03/02/1987	FERROELECTRIC LIQUID CRYSTAL DISPLAY DEVICE HAVING A SINGLE POLARIZER	SAKAMA, mitsunori
X 07000775	Not Issued	166	01/06/1987	LIQUID CRYSTAL DEVICE WITH AN APPARENT HYSTERESIS	SAKAMA, mitsunori
X 07000155	4744862 Au 1303 156/652	150	01/02/1987	MANUFACTURING METHODS FOR NONLINEAR SEMICONDUCTOR ELEMENT AND LIQUID CRYSTAL DISPLAY PANEL USING THE SAME	SAKAMA, mitsunori
X 06830184	Not Issued	161	02/18/1986	DOT MATRIX TYPE LIQUID CRYSTAL DISPLAY APPARATUS	SAKAMA, mitsunori
X 06830183	Not Issued	161	02/18/1986	METHOD FOR DRIVING A DOT MATRIX TYPE LIQUID CRYSTAL DISPLAY APPARATUS	SAKAMA, mitsunori
X 06821840	4730903	150	01/23/1986	FERROELECTRIC LIQUID CRYSTAL DISPLAY PANEL AND MANUFACTURING METHOD THEROF	SAKAMA, mitsunori
X 06813515	Not	166 abd	12/26/1985	ELECTRONIC DEVICE AND	SAKAMA,



	Issued			ITS MANUFACTURING METHOD	ITSUNORI
<u>06797003</u>	Not Issued	166	11/12/1985	LIQUID CRYSTAL DISPLAY PANEL AND MANUFACTURING METHOD THEREOF	SAKAMA , ITSUNORI
<u>06782628</u>	Not Issued	166	10/01/1985	NONLINEAR SEMICONDUCTOR ELEMENT, LIQUID CRYSTAL DISPLAY PANEL USING THE SAME AND THEIR MANUFACTURING METHODS	SAKAMA , ITSUNORI
<u>06725596</u> 118/119	4936251 Au 1801	150	04/22/1985	VAPOR-PHASE REACTION APPARATUS	SAKAMA , ITSUNORI

[Search and Display More Records.](#)

**Search Another: Inventor**

**Last Name**

**First Name**

sakama

mitsunori

**Search**

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

Day : Friday  
Date: 12/19/2003

 PALM INTRANET

Time: 12:28:13

**Inventor Name Search Result**

Your Search was:

Last Name = SAKAMA

First Name = MITSUNORI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 3
<del>08068184</del>	Not Issued	166 <i>abd</i>	05/28/1993	ETCHING APPARATUS	SAKAMA , MITSUNORI
07203641	4855805 <i>Mr 2503 999/58</i>	150	06/03/1988	NONLINEAR SEMICONDUCTOR ELEMENT, <u>LIQUID CRYSTAL DISPLAY</u> PANEL USING THE SAME AND THEIR MANUFACTURING METHODS	SAKAMA , MITSUNORI
<del>06830184</del>	Not Issued	161 <i>abd</i>	02/18/1986	DOT MATRIX TYPE LIQUID CRYSTAL DISPLAY APPARATUS	SAKAMA , MITSUNORI

**Inventor Search Completed:** No Records to Display.

**Search Another: Inventor**

<b>Last Name</b>	<b>First Name</b>	
<input type="text" value="sakama"/>	<input type="text" value="mitsunori"/>	<input type="button" value="Search"/>

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	35	(("20020111040") or ("20020006711") or ("20030066485") or ("20030151119") or ("6499427") or ("6673659") or ("6632708") or ("6482752") or ("5330578") or ("5079031") or ("4723508") or ("6283060") or ("5837614") or ("6228751") or ("6323142") or ("6337229") or ("5840600")).PN.	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2003/12/1 9 14:04
2	L2	1287	(427/563,574,578,579).CCLS	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:37
3	L3	1663	(438/485-487,788,789,792-793).CCLS.	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:37
4	L4	953	((("438/761,763").CCLS.) and (plasma or glow adj discharge)	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:38
5	L5	3517	2 or 3 or 4	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2003/12/1 9 14:38

SN09/070,908

2

	L #	Hits	Search Text	DBs	Time Stamp
6	L6	2438	(((((("427/563,574,578,579" ).CCLS.) or (("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and pressure) or ((((("427/563,574,578,579") .CCLS.) or (("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and ((gas gases rate) near2 (flow input)))) and (plasma or glow adj discharge)	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:40
7	L7	3536	((("427/563,574,578,579").C CLS.) or (("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge)))	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:42
8	L8	2504	(((((("427/563,574,578,579"). CCLS.) or (("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and pressure	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:43
9	L9	1534	(((((("427/563,574,578,579"). CCLS.) or (("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and ((gas gases rate) near2 (flow input)))	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:44

	L #	Hits	Search Text	DBs	Time Stamp
10	L10	2606	(((("427/563,574,578,579") .CCLS.) or ("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and pressure) or (((("427/563,574,578,579") .CCLS.) or ("438/485-487,788,789,792 -793").CCLS.) or (((("438/761,763").CCLS.) and (plasma or glow adj discharge))) and ((gas gases rate) near2 (flow input)))	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/12/1 9 14:44